

# Single photon timing resolution and detection efficiency of the ITC-IRST silicon photo-multipliers

Gianmaria Collazuol

Scuola Normale Superiore and INFN Pisa

on behalf of

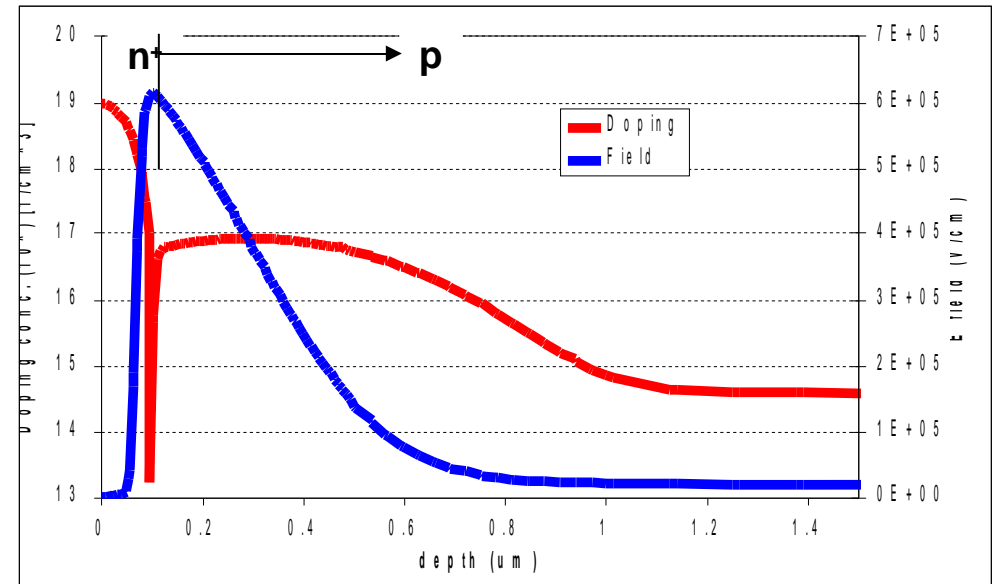
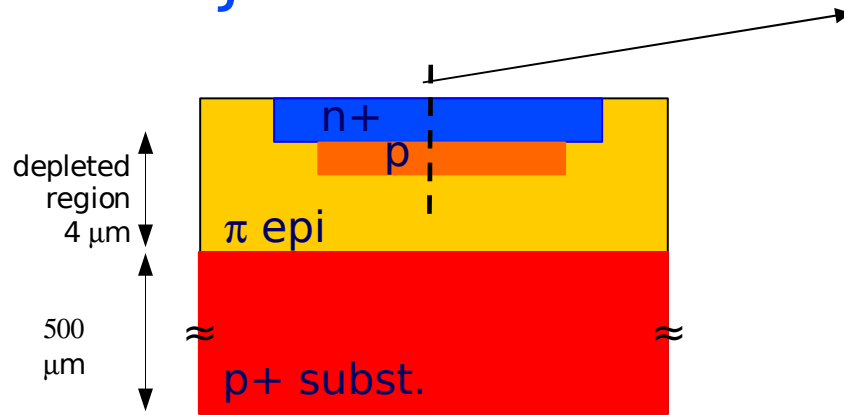
G.Ambrosi, M.Boscardin, F.Corsi, G.F.Dalla Betta, A.Del Guerra,  
M.Galimberti, D.Giulietti, L.A.Gizzi, L.Labate, G.Llosa, S.Marcatili,  
C.Piemonte, A.Pozza, N.Zorzi

# Overview

- The SiPM devices produced at IRST
- Photodetection efficiency
- Single photon timing resolution
- Energy resolution of SiPM coupled to LSO
- Next steps, improvements and Conclusions

# The IRST SiPM technology

## The SiPM building block Shallow-Junction GM-APD



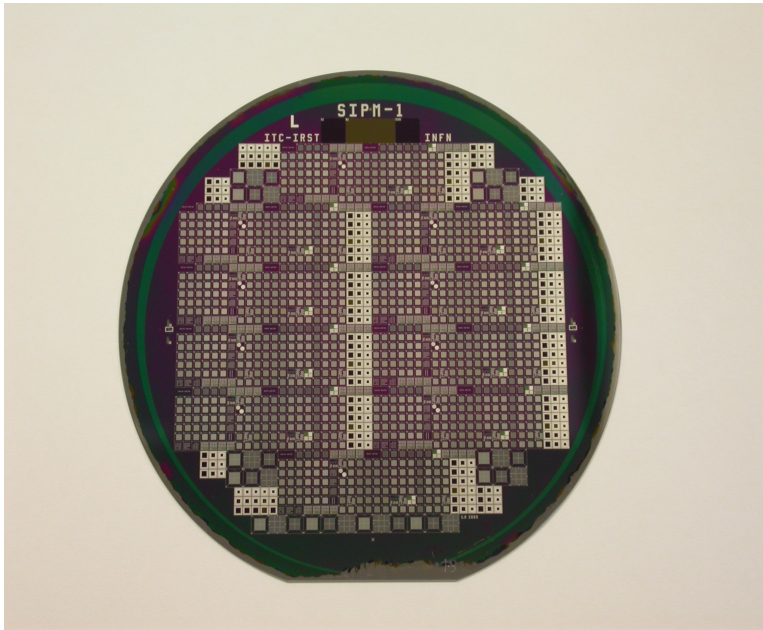
## Optimization for the blue light (420nm)

- 1) Substrate: p-type epitaxial
- 2) **Very thin (100nm) n+ layer**
- 3) Quenching resistance made of doped polysilicon
- 4) Anti-reflective coating (ARC) optimized for  $\lambda \sim 420\text{nm}$
- 5) **Geometry (fill factor) NOT yet optimized for maximum PDE**
- 6) Trenches for optical insulation of cell (**low cross-talk**)

# The IRST technology

Since the beginning of project (2005) **three batches with the same layout** have been produced:

- to verify functionalities and **reproducibility** of the production processes
- to study the technology for **dark count rate** and **reducing optical cross-talk**
- to investigate the **photodetection efficiency**

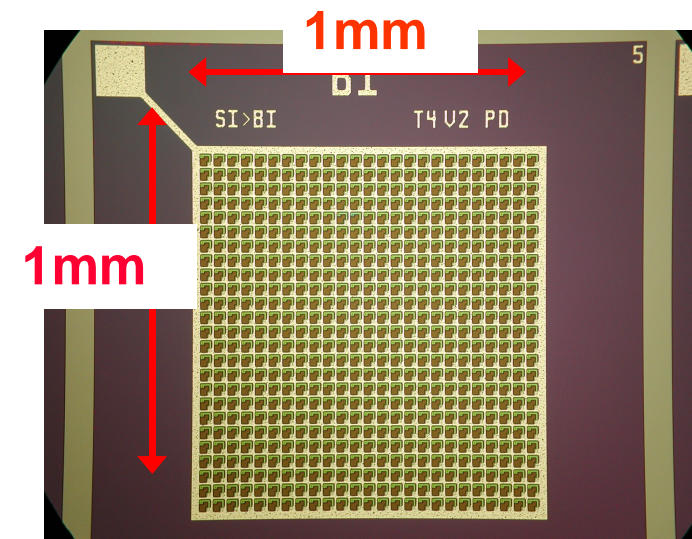


The wafer layout includes many structures:

- SiPMs
- single GM-APDs
- “large-area” diodes (no  $R_{\text{quench}}$ )
- + several test structures

Basic SiPM geometry:

- **25x25 cells**
- **cell size:  $40 \times 40 \mu\text{m}^2$**



# Characterization of the devices

related to the **recharge of the diode capacitance** from  $V_{BD}$  to  $V_{bias}$  during the avalanche quenching time after  $I_{latch}$  is reached.

$$G = (V_{BIAS} - V_{BD}) * C_D / q$$

valid for few volts above  $V_{BD}$

Gain

pulses triggered by non-photogenerated carriers (**thermal generation** in the bulk or in the surface depleted region around the junction)

**carriers can be trapped** during an avalanche and then released triggering another avalanche

Noise: dark count  
afterpulse  
optical cross-talk

**photo-generation during the avalanche discharge.** Some of the photons can be absorbed in the adjacent cell possibly triggering new discharges

$$PDE = QE * P_{trigg} * \epsilon_{geom}$$

QE = quantum efficiency

$P_{trigg}$  = avalanche triggering prob.

$\epsilon_{geom}$  = geometrical fill factor

Photodetection efficiency

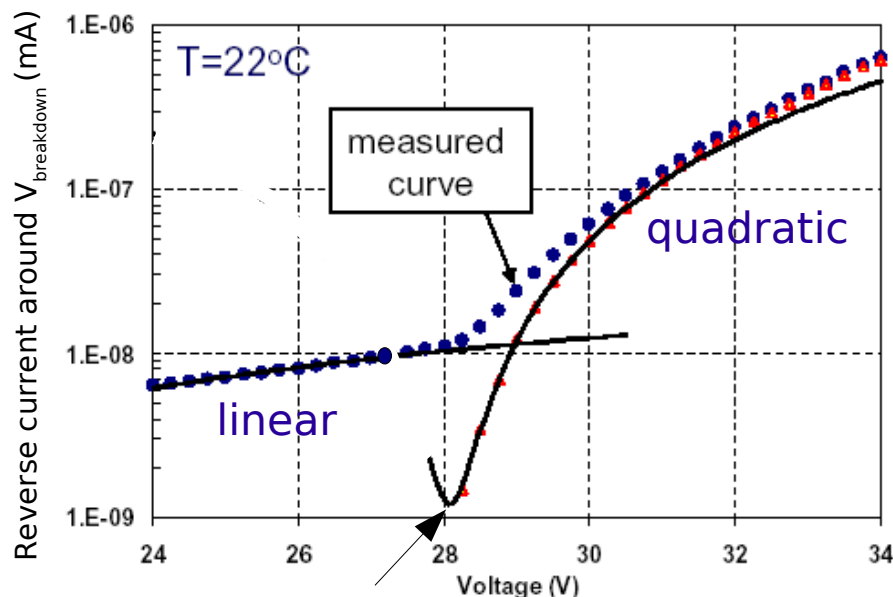
Time resolution

Related to the photogeneration and to the **avalanche propagation**

# Static characteristics (I-V measurement)

Fast tests to verify the functionality of the device:

- Breakdown voltage ( $V_{bd}$ )
- Dark count rate ( $N_{dark}$ )
- Quenching resistor value  $R_Q$

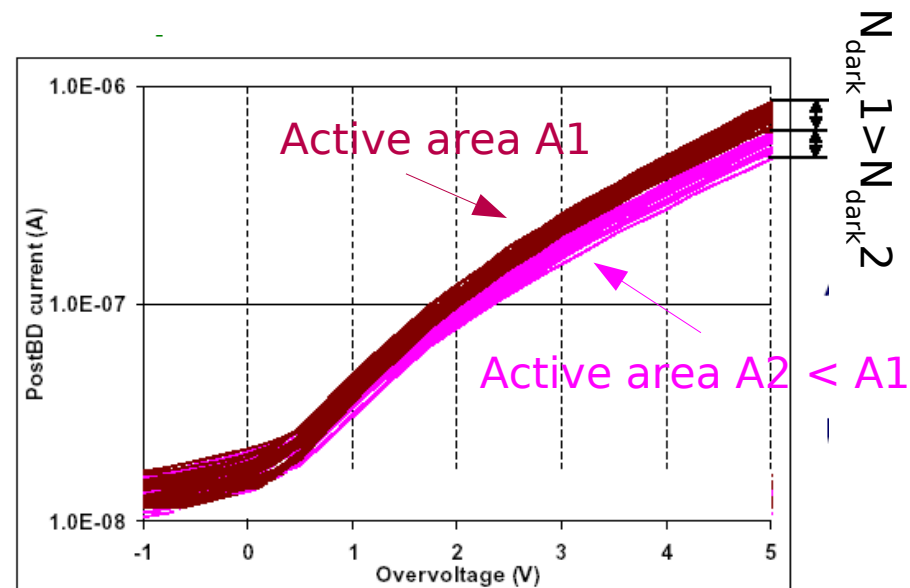


**Pre-breakdown:** current mainly due to generation in the surface region around diode:

$$I_{pre-BD} \sim V_{bias} \text{ (linear)}$$

**Post-breakdown:** up to few V current due dark events is:

$$I_{post-BD} = q \cdot G \cdot N_{dark} \sim q \cdot V_{bias} \cdot V_{bias} \text{ (quadratic)}$$



- **Uniform breakdown voltage** in a wafer and from wafer to wafer.
- post-breakdown current very uniform  $\rightarrow$  **uniform dark count rate**
- less than **20% of the devices show anomalous** current behavior ( $\sim 1000$  devices measured)

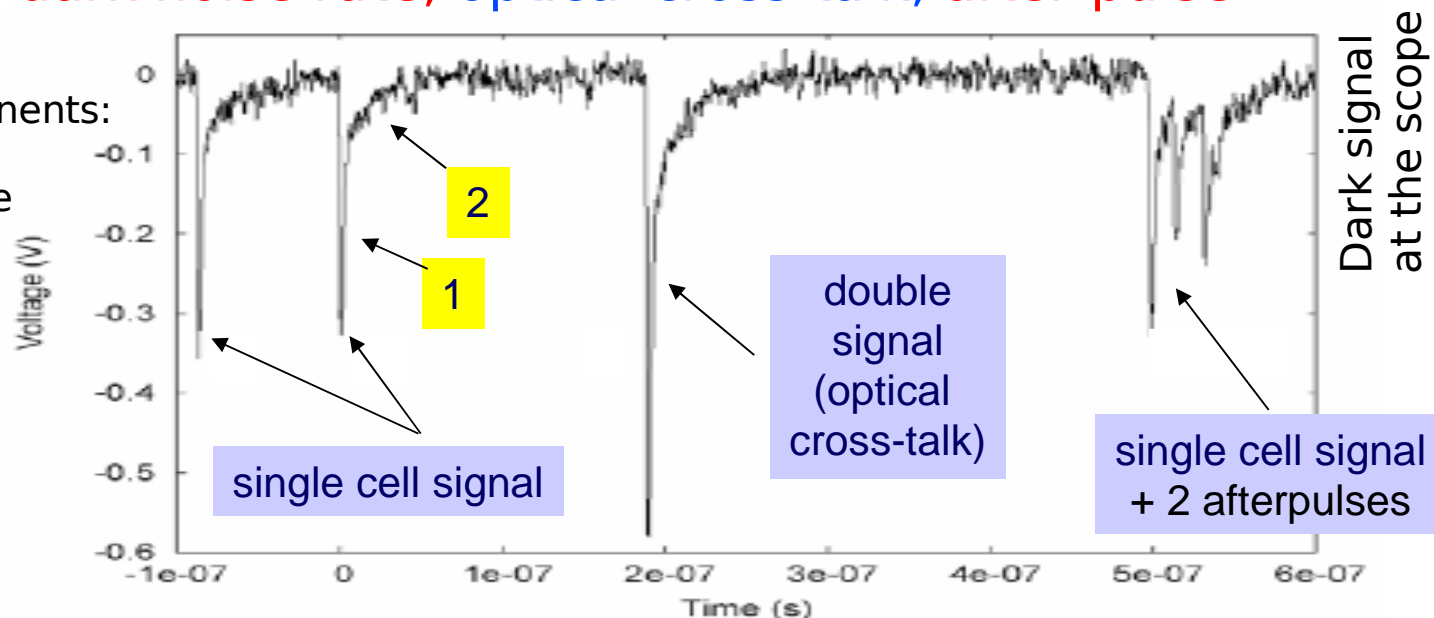
# Dynamic characteristics

Complete characterization of signal and noise:

Signal shape, gain, dark noise rate, optical cross-talk, after-pulse

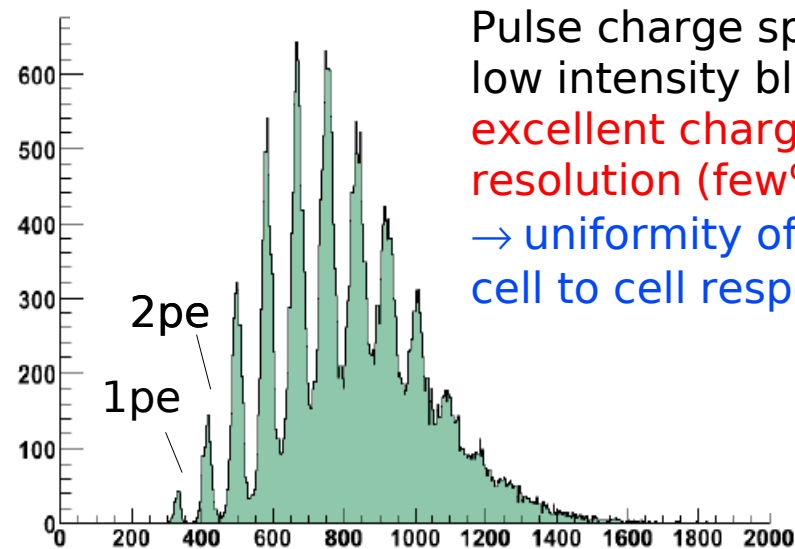
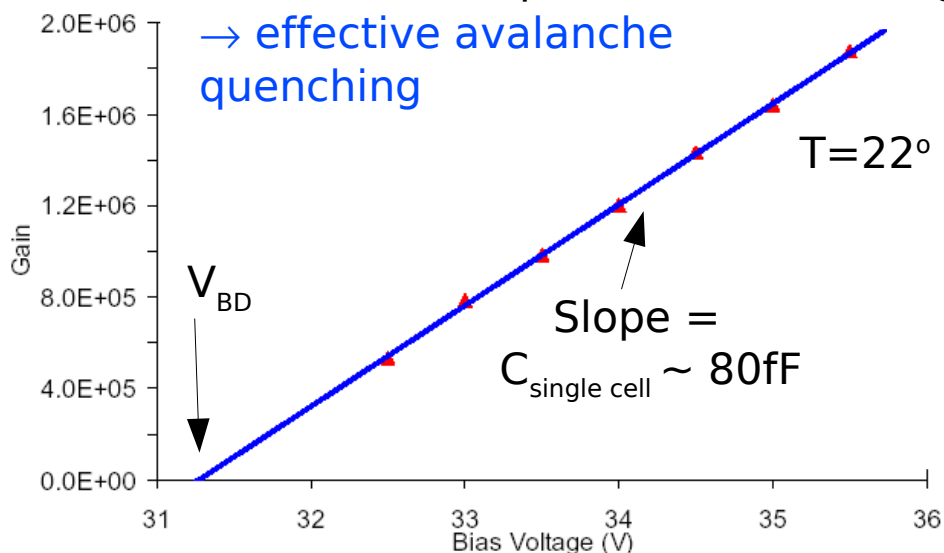
The signal presents 2 components:

1. **fast component:** avalanche current reproduced at the output by parasitic capacitor
2. **slow component** due to the recharge of the diode capacitance (recovery time  $\sim 70\text{ns}$ )



Gain is linear up to  $\sim 5\text{V}$  overvoltage

$\rightarrow$  effective avalanche quenching



Pulse charge spectrum  
low intensity blue LED  
excellent charge resolution (few%)  
 $\rightarrow$  uniformity of cell to cell response

# Photodetection efficiency (PDE)

$$PDE = N_{\text{pulses}} / N_{\text{photons}} =$$

## Carrier Photogeneration

(QE = probability for a photon to generate a carrier that reaches the high field region)

\*

## Avalanche triggering

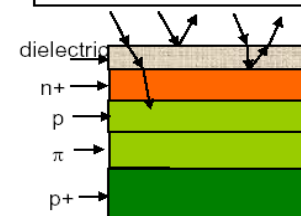
( $P_{\text{trigg}}$  = probability for a carrier traversing the high-field to generate the avalanche)

\*

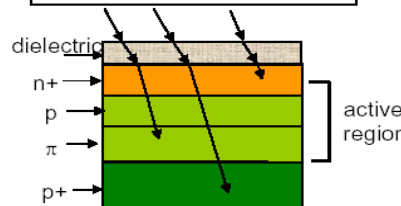
## Geometrical factor

( $\epsilon_{\text{geom}}$  = fraction of dead area due to structures between the cells, eg. guard rings, trenches)

a. Transmission efficiency



b. Internal quantum efficiency



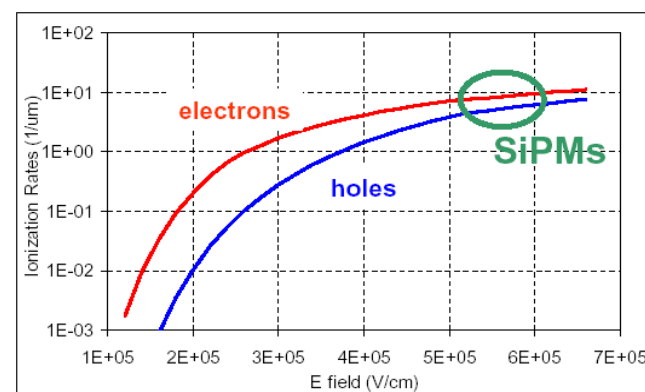
## Optimization

- Anti-reflective coating (ARC)

- Shallow junctions for short  $\lambda$
- thick epi layers for long  $\lambda$

- high overvoltage
- photogeneration in the junction p-side

## Ionization rate in Si



W.Oldham et al. IEEE Trans. ED (1972)

C.Piemonte, NIM A568 (2006) 224-232



# Experimental Method

Two methods: DC current and Pulses count

$$(1) \quad N_{\text{det. photons}} [s^{-1}] = \frac{I_{\text{light}} - I_{\text{dark}}}{q \cdot G}$$

$$(2) \quad N_{\text{det. photons}} [s^{-1}] = \text{Rate}_{\text{light}} - \text{Rate}_{\text{dark}}$$

$$\text{PDE} = \frac{N_{\text{detected photons}}}{N_{\text{incident photons}}}$$

Reference by calibrated detector  
(photodiode)

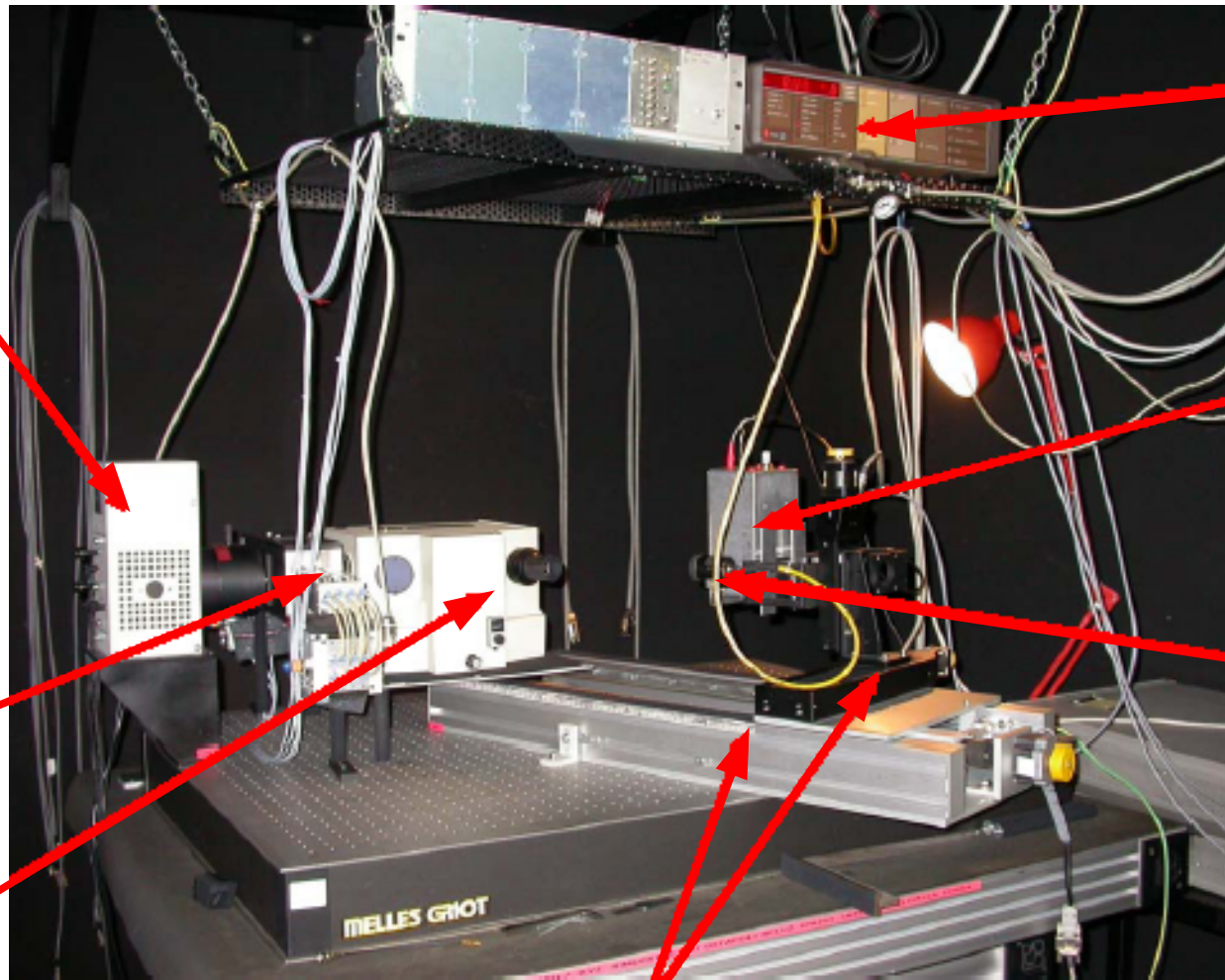
$$N_{\text{incident photons}} [s^{-1} \text{mm}^{-2}] = \Phi_{[W/\text{mm}^2]} \frac{\lambda}{hc}$$

$$\Phi_{[W/\text{mm}^2]} = \alpha_{[W/A]} \frac{I_{[A]}}{S_{[\text{mm}^2]}}$$

NOTE:

- Rate effects, **afterpulses**, and **cross-talk** must be properly taken into account. Easier for method (2).
- Method (1) needs also **Gain** to be measured.
- Method (2): rates of counts above  $0_{pe}$  can be measured. As an alternative the rate of  **$0_{pe}$**  in proper gate can be used to measure  $N_{pe}$  following Poisson statistics

# Experimental Setup (IRST)



Halogen  
white lamp

Neutral filters  
(transmittance  
10%)

Monocromator

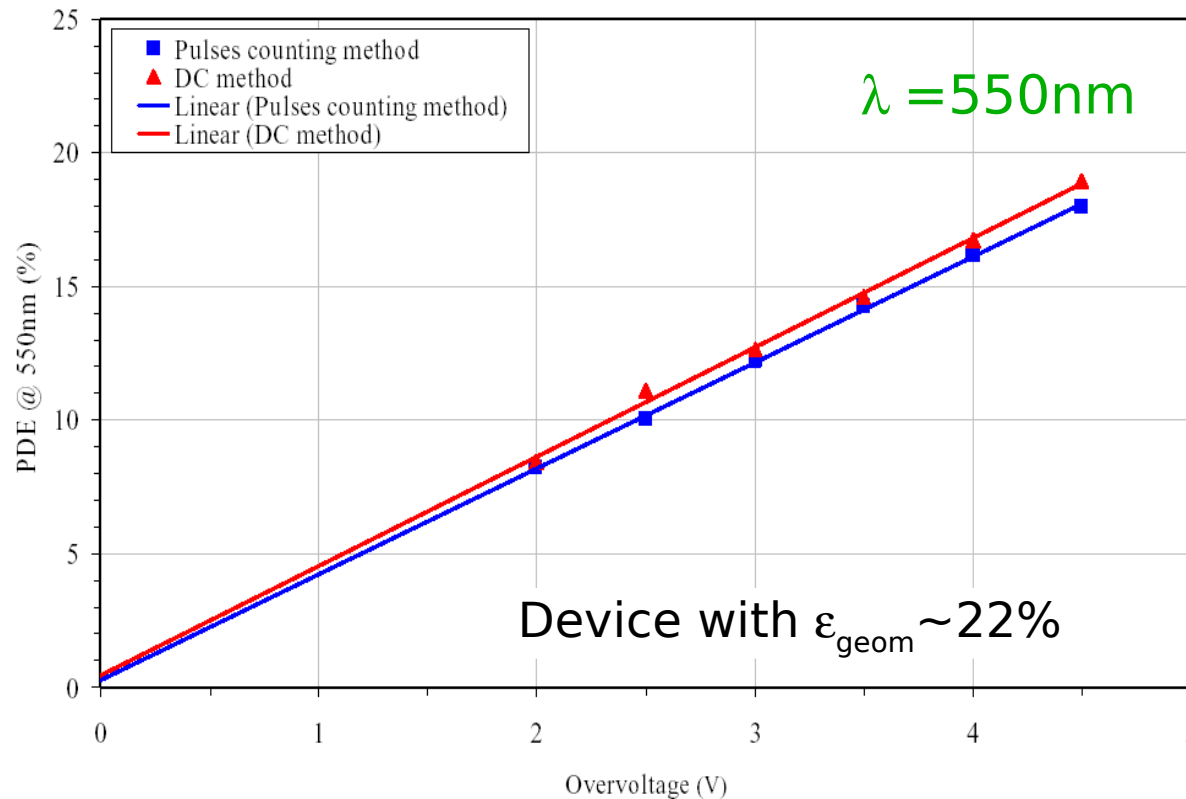
Optometer

SiPM+  
preamplifier

Photodiode  
UDT221

Stage with 3D micrometers movement (50um precision)

# PDE measurement: DC vs Pulse methods

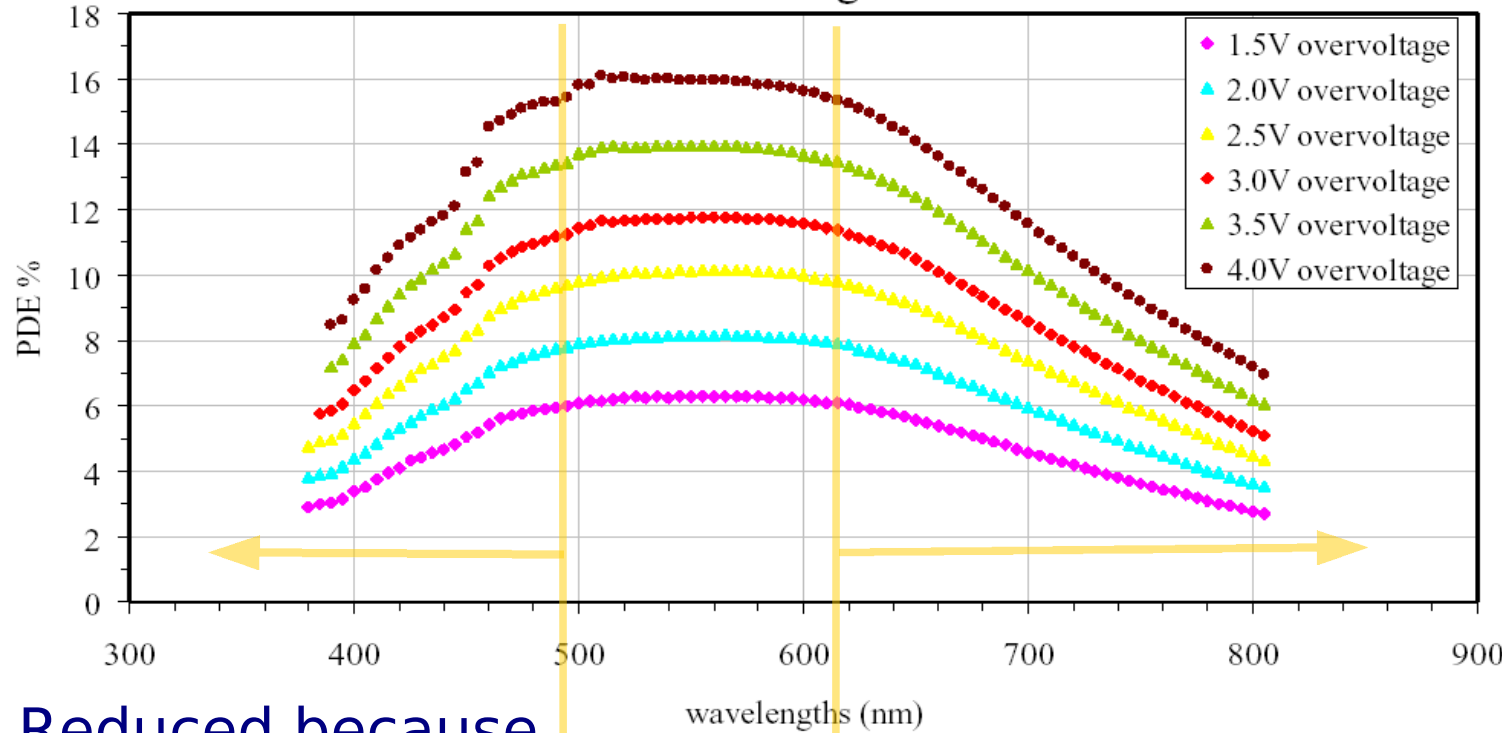


- Agreement between the two methods
- PDE ~ linear with overvoltage

# PDE vs wavelength

device with  $\epsilon_{\text{geom}} \sim 22\%$  **not yet optimized !!!**

Flat factor



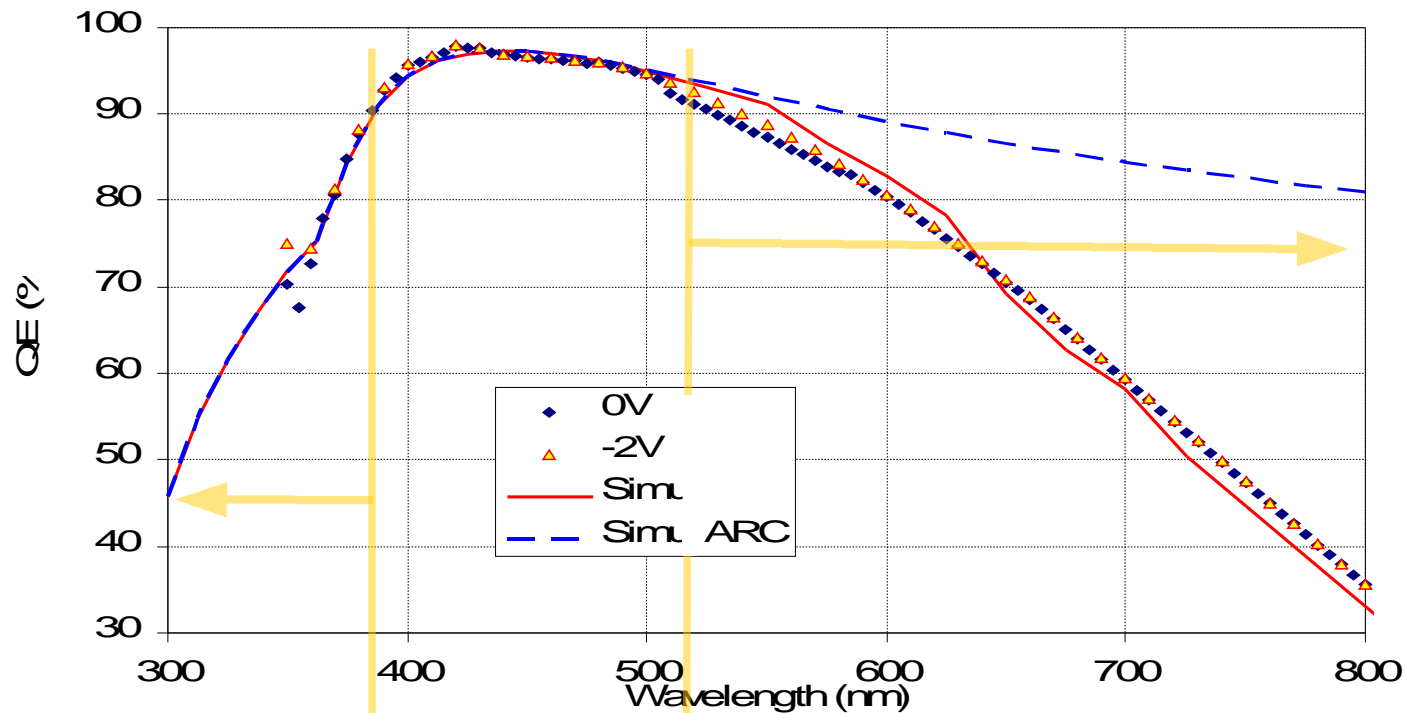
Reduced because avalanche triggered by holes

Reduced because low QE

# PDE of a single diode (photovoltaic regime)

Disentangling the 3 PDE components: no  $P_{trigg}$  and fill factor  $\epsilon_{geom}$  here !

Direct access to **internal QE** and **transmission trough ARC** by measuring ( $V_{bias} \sim \text{few V}$ ) photon detection efficiency of a diode with the same  $n^+/p$  junction structure and same ARC

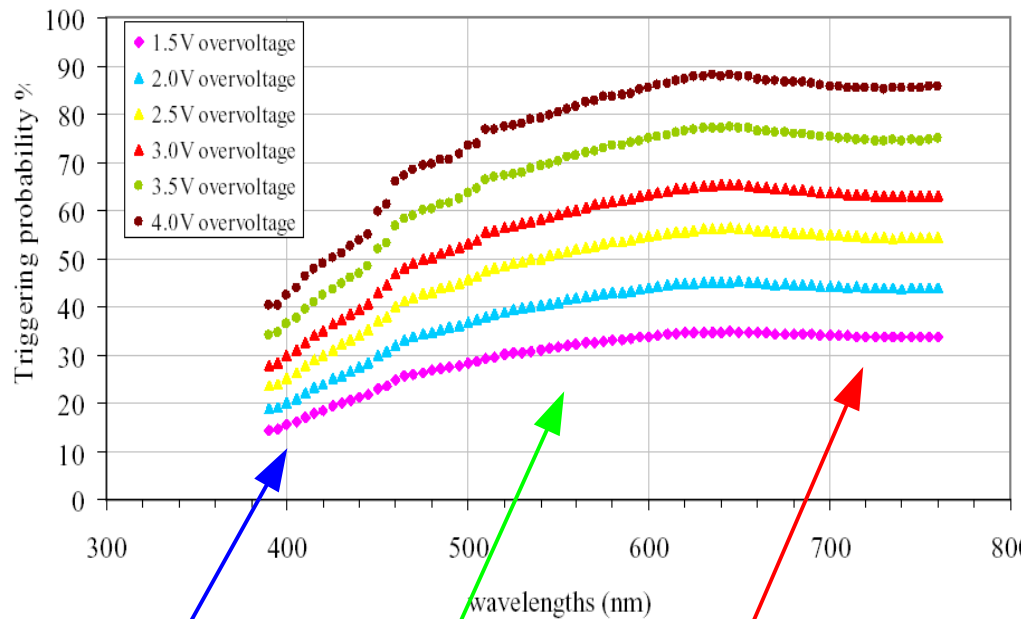


Reduced by  
ARC Transmission

Reduced by  
small epi layer thickness

# Avalanche trigger probability

$$P_{trigg} = PDE / QE / \epsilon_{geom.}$$

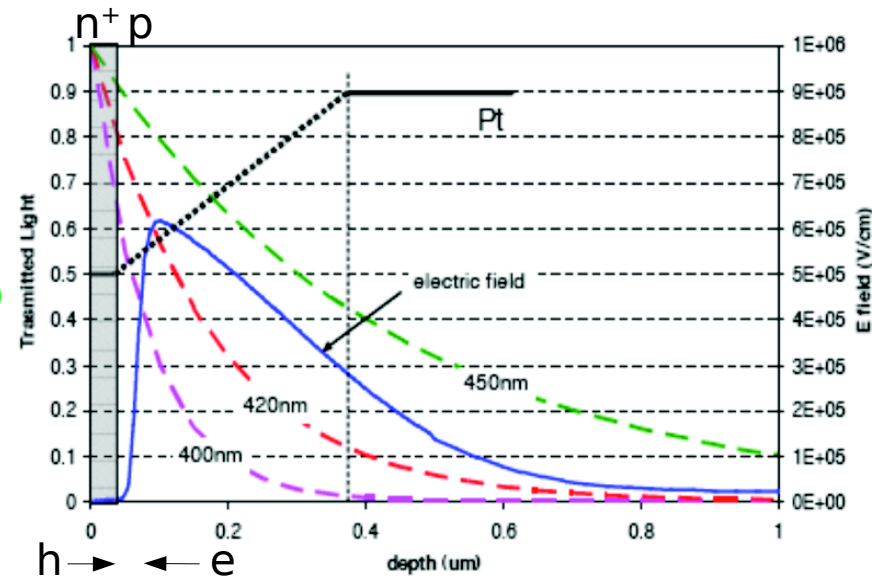
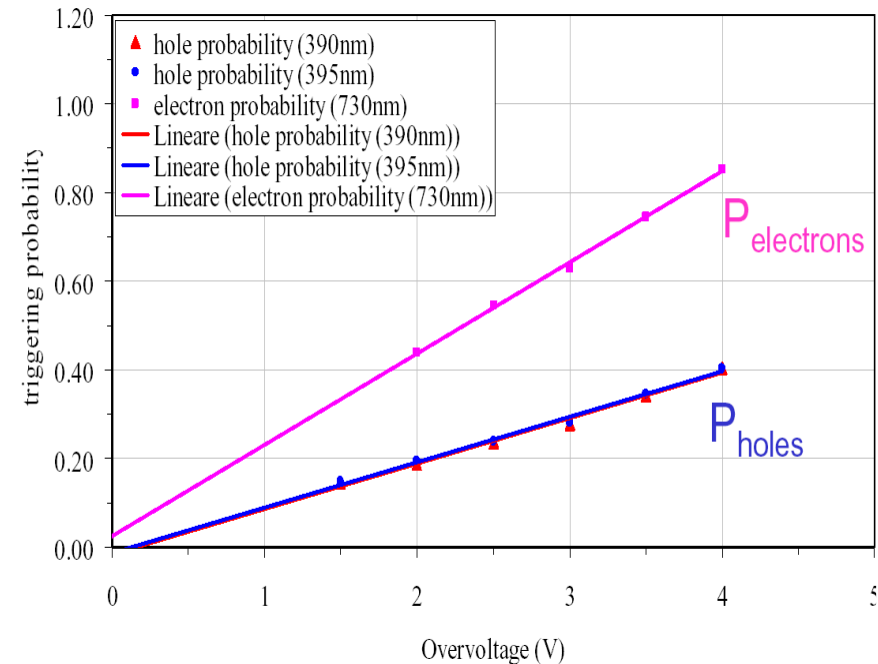


Only e<sup>-</sup> cross the high E field region and trigger the avalanche

Both h<sup>+</sup> and e<sup>-</sup> might trigger the avalanche (but cross only a fraction of high field region)

Only h<sup>+</sup> cross the high E field trigger the avalanche

$PDE \sim P_{trigg} \sim$  linear with overvoltage



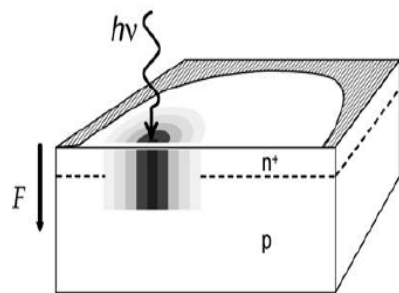
# Single photon timing resolution

Detailed studies about timing of Single Photon Avalanche Diodes (SPAD) by Cova et coll.

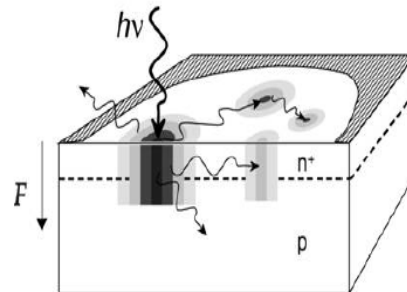
Fast component (time scale few 10ps)  
main resolution peak width

Statistical fluctuations in the Avalanche:

- **Vertical** build-up (**minor** contribution)
- **Horizontal** propagation (**major** contribution)
  - via Multiplication assisted diffusion (dominating contribution)  
A.Lacaita et al. APL and EI.Lett. 1990
  - via Photon assisted propagation  
PP.Webb, R.J. McIntyre RCA Eng. 1982  
A.Lacaita et al. APL 1992



Multiplication assisted diffusion

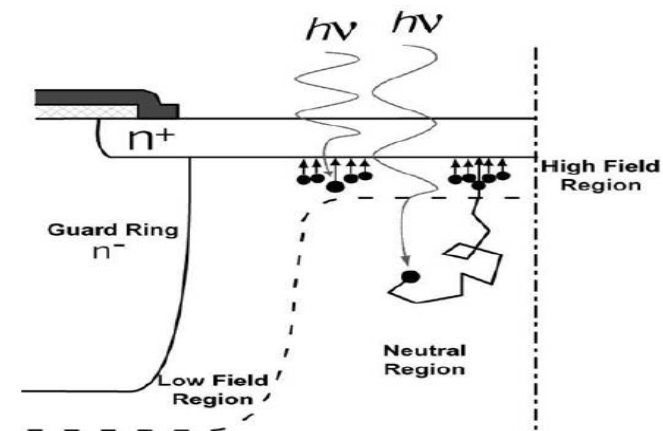


Photon assisted propagation

Slow component (time scale ns)  
minor non gaussian tails

Carriers photogenerated in the neutral regions beneath the junction and reaching the electric field region by diffusion

G.Ripamonti, S.Cova Sol.State Electronics (1985)



tail lifetime:  $\tau \sim L^2 / \pi^2 D$

L = effective neutral layer thickness

D = diffusion coefficient

S.Cova et al. NIST Workshop on SPD (2003)

High overvoltage → improved time resolution

Higher resolution for short wavelengths

# Experimental Method

- SiPM exposed to **pulsed femto-second laser** in low light intensity conditions (single photon)
- SiPM signal is sampled at high rate and the time of the pulses measured by **waveform analysis**
- Time resolution measured by studying the distribution of **time differences between successive pulses** (on the same SiPM device)



# Experimental Setup (CNR Pisa)

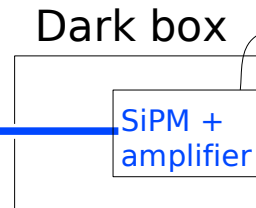
## Pump Laser

*Millenia V (Spectra-physics)*  
solid state CW visible laser

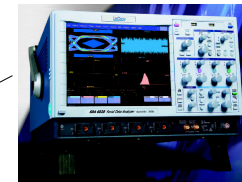


## Crystal for Second Harmonic Generation (SHG)

conversion  $800 \text{ nm} \rightarrow 400 \text{ nm}$   
efficiency at % level



Low noise LV suppliers



## LeCroy SDA 6020

Analog bandwidth: 6GHz  
Sampling rate: 20GS/s  
Vertical resolution: 8 bits

(Acknowledgments:  
E.Marcon, LeCroy)

External trigger from  
Ti:sapphire laser  
signal

## Mode-locked Ti:sapphire Laser

*Tsunami (Spectra-physics)*  
femtosecond pulsed laser

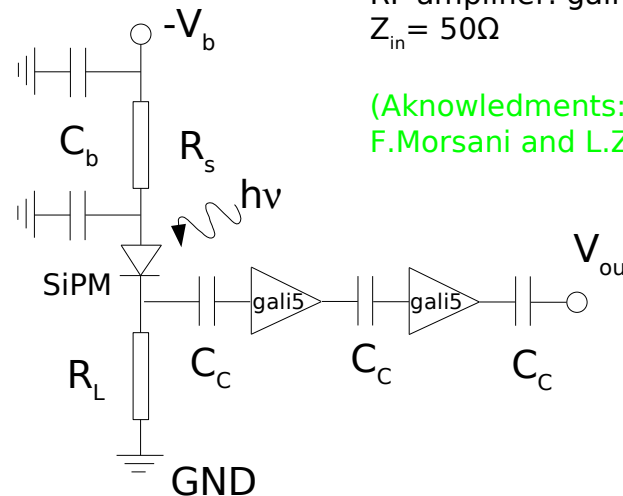
wavelength: tuned at  $800 \pm 15 \text{ nm}$   
pulse width:  $\sim 60 \text{ fs}$   
pulse period:  $\sim 80 \text{ MHz}$   
pulse timing jitter  $< 100 \text{ fs}$

Filters  
blue + neutral  
for rejecting IR light  
and tune intensity

## Electronics

$I \rightarrow V$  conversion via  $R_L$  ( $500 \Omega$ )  
Two stage voltage amplification (= x50)  
based on high-bandwidth low-noise  
RF amplifier: gali-5 (MiniCircuit)  
 $Z_{in} = 50 \Omega$

(Acknowledgments:  
F.Morsani and L.Zaccarelli, INFN-Pisa)



## Data taking conditions:

- different  $V_{bias}$
- both at  $800 \text{ nm}$  and  $400 \text{ nm}$
- with different light intensities  
(counting rates  
in the range  $10 \div 20 \text{ MHz}$   
ie  $15 \div 30 \text{ KHz per single cell}$ )

# Waveform analysis

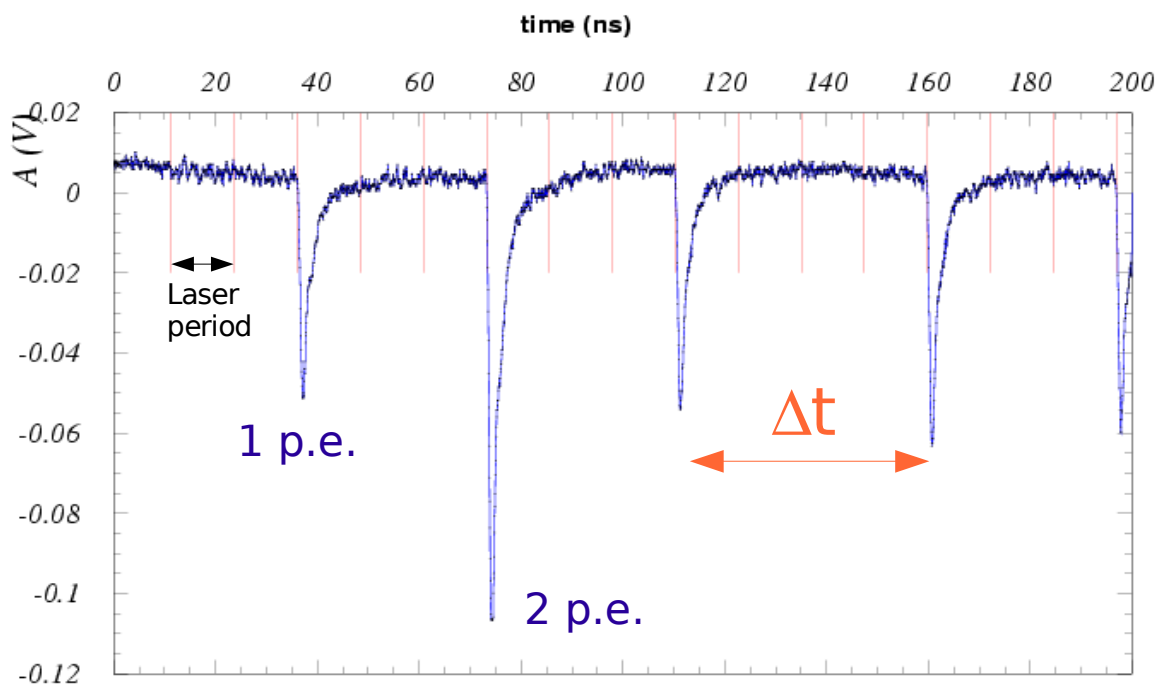
(1) Selection of candidate peaks:

- single photon peaks
- proper signal shape
- **low instantaneous intensity**  
(no activity before/after within 50ns)
- **low noise** during the previous 10 ns  
(typical noise  $\sim 1\text{mV rms}$ )

(2) Peak reconstruction

- **optimum time reconstruction**
- amplitude and width (baseline shift correction)

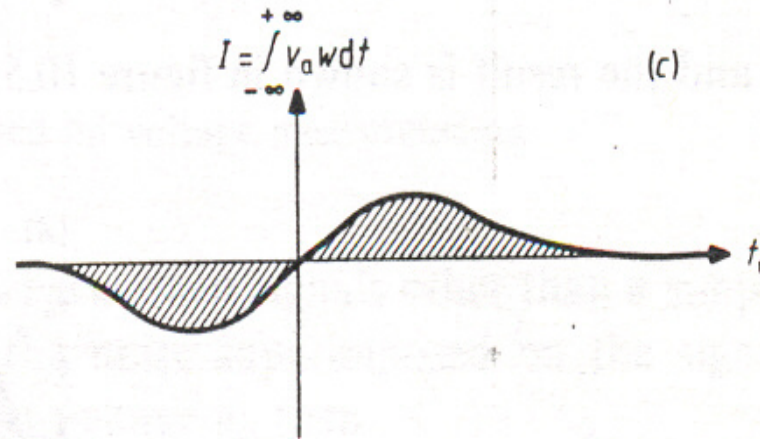
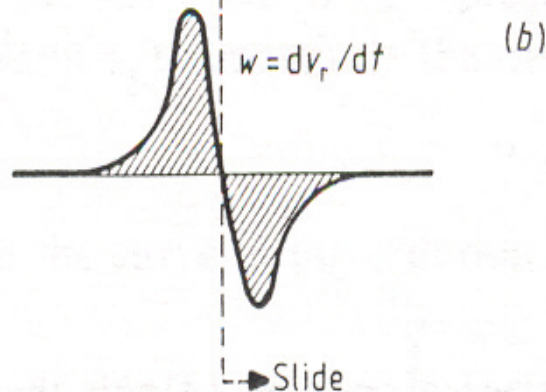
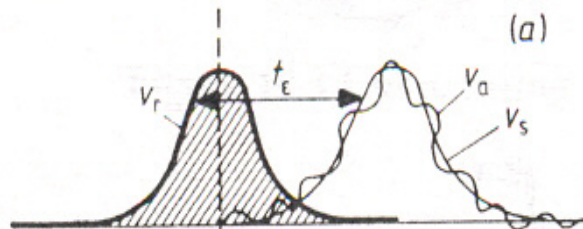
(3) Time difference  $\Delta t$  between consecutive peaks



# Waveform analysis: time reconstruction

Different methods to reconstruct the time of a peak:

- ✗ parabolic fit to find the peak maximum
- ✗ average of time samples weighted by the waveform derivative
- ✓ digital filter: weighting by the derivate of a reference signal  
→ best against noise (signal shape known)



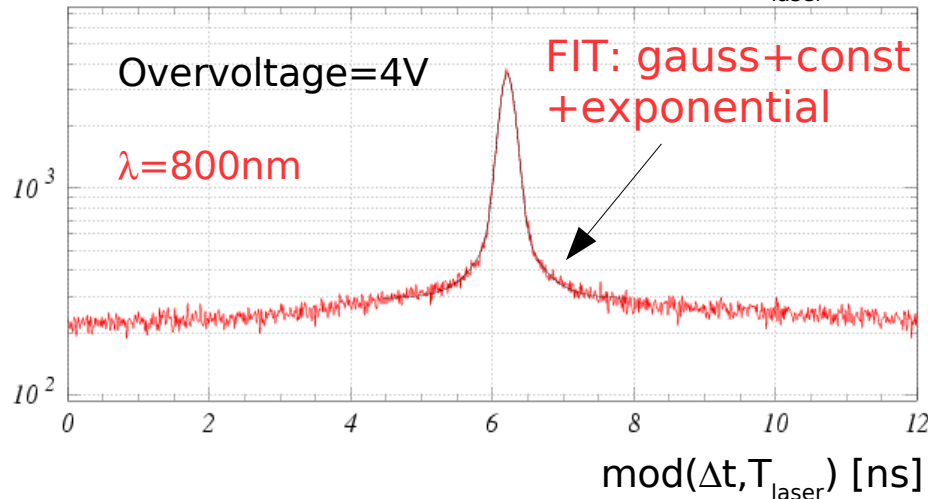
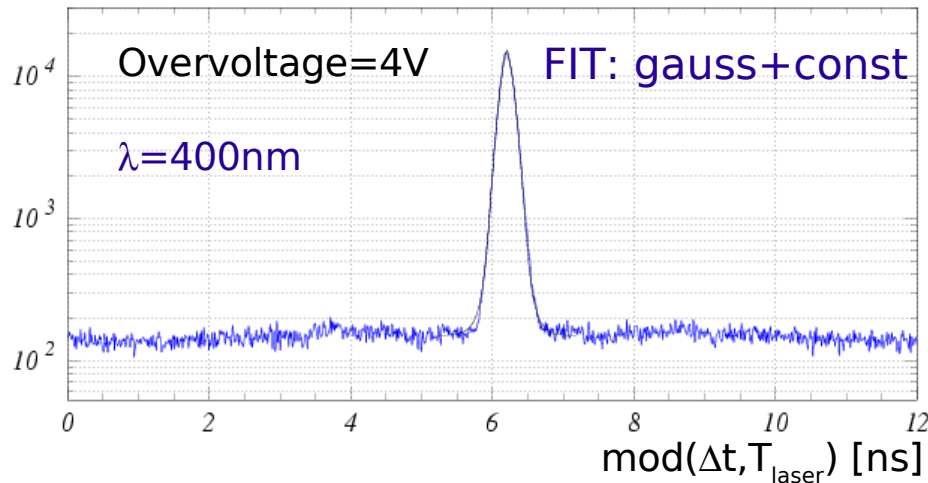
Digital filter method to minimize N/S for timing measurements:  
solve the following equation on  $t_0$  :

$$\int V_a(t) \frac{\partial V_r(t-t_0)}{\partial t} dt = 0$$

$V_a$  = measured signal  
(includes noise)  
 $V_r$  = reference signal  
 $t_0$  = reference time

# Distribution of the time differences

Distributions of the difference in time between successive peaks (modulo the measured laser period  $T_{\text{laser}} = 12.367\text{ns}$ )



Data at  $\lambda=400\text{nm}$   
fit gives reasonable  $\chi^2$   
with gaussian ( $\sigma_t^{\text{fit}}$ ) +  
constant term (dark  
noise contribution)

The detector  
resolution is obtained  
by  $\sigma_t^{\text{fit}}/\sqrt{2}$

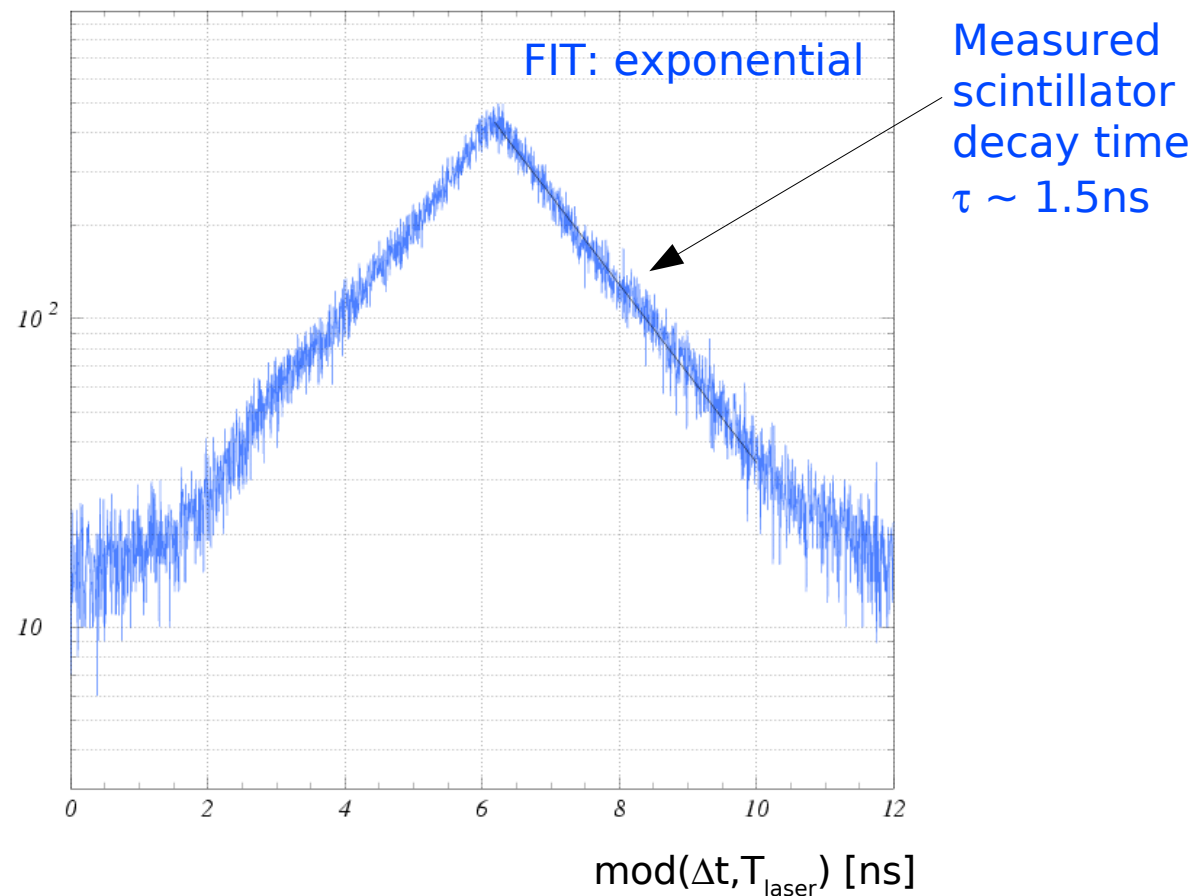
Data at  $\lambda=800\text{nm}$   
fit gives reasonable  $\chi^2$  with an  
additional **exponential term**  $\exp(-\Delta t/\tau)$

- $\tau \sim 0.2 \div 0.8\text{ns}$  in rough agreement  
with diffusion tail lifetime:  $\tau \sim L^2 / \pi^2 D$   
if  $L$  is taken to be the diffusion length
- Contribution from the tails  $\sim 10 \div 30\%$   
of the resolution function area  
(to be studied in detail: WORK in PROGRESS)

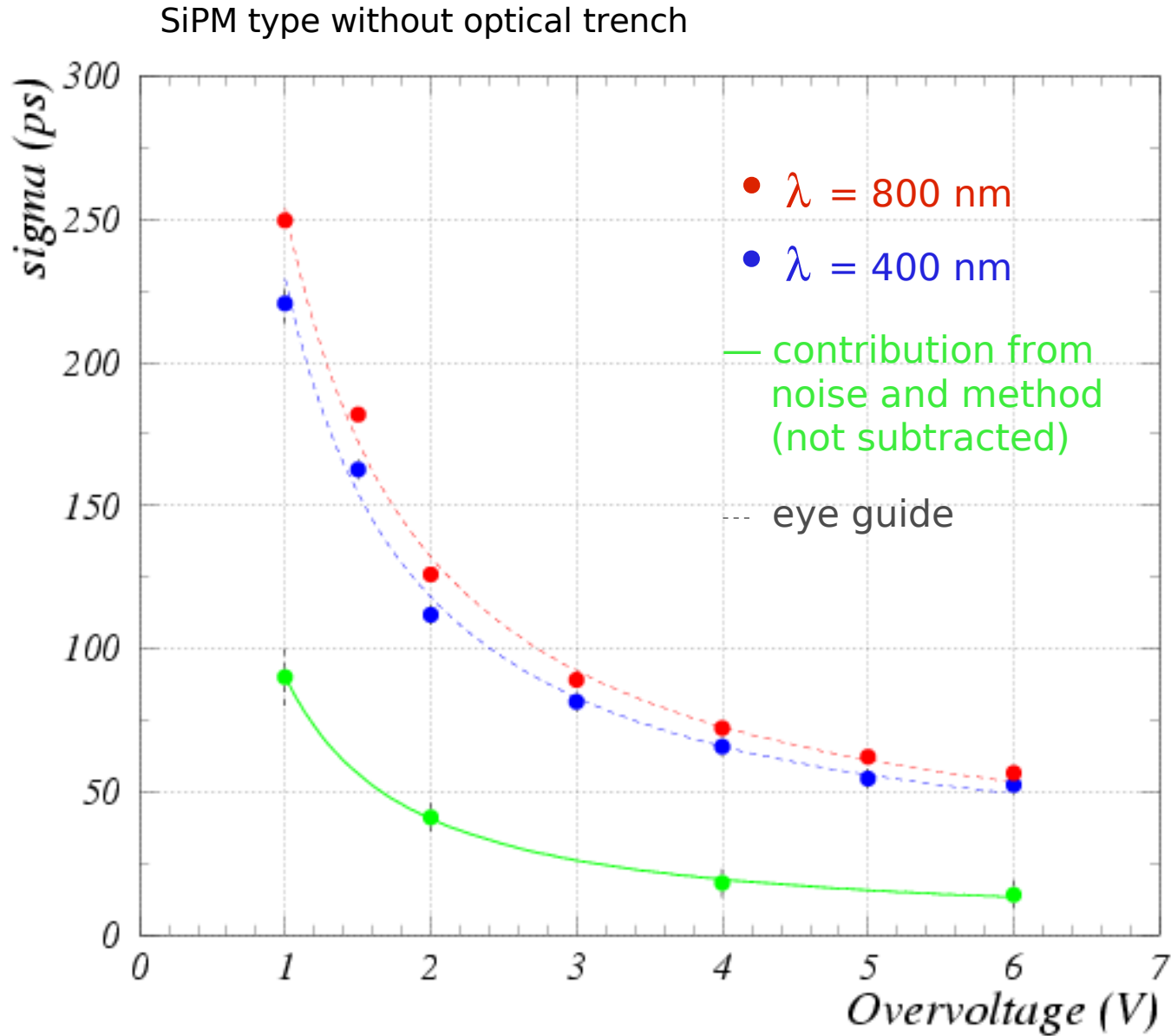
# Time differences distribution

Cross check: SiPM coupled to a fast plastic scintillator  $2 \times 2 \times 15\text{mm}^3$   
Only the scintillator exposed to the laser blue light  $\lambda=400\text{nm}$ .  
No direct laser light to the SiPM

→ measurement of the scintillator decay tail



# Results on IRST devices: gaussian $\sigma_t$



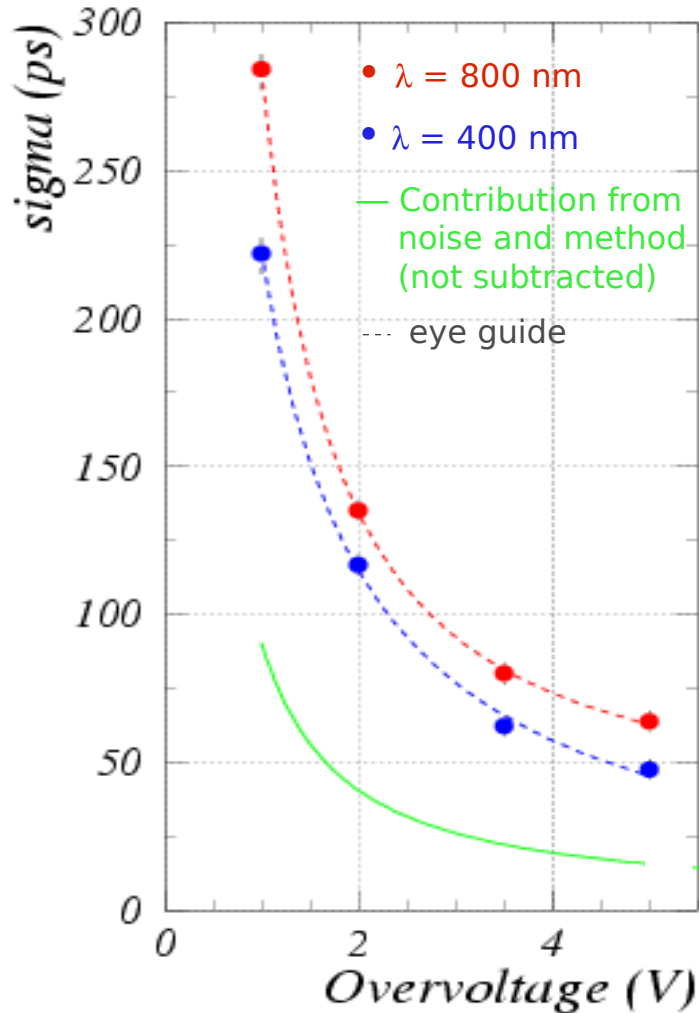
# Systematics

- Contribution (main) from the electronic noise:
  - (1) directly measured by splitting in two the signal of the SiPM, delaying one and recombine the two signals again. Measure the (fixed) time difference.
  - (2) cross-check by doubling the noise and measuring the effect on the resolution

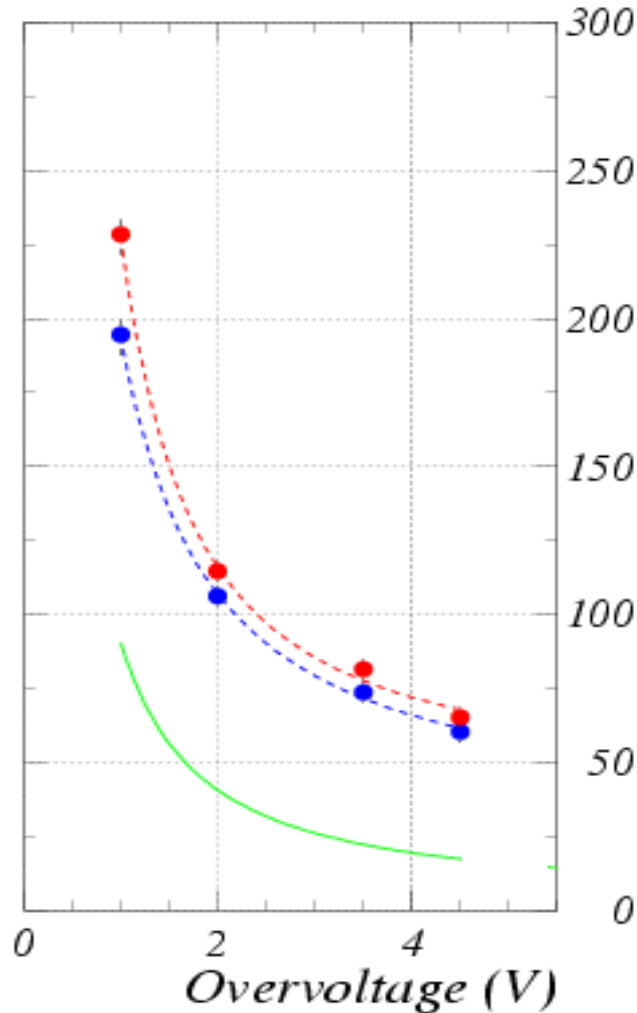
This contribution includes also the systematics related to the method of time reconstruction by waveform analysis
- Contribution from sampling hardware (clock jitter, ...)  $< 5\text{ps}$
- Sensitivity to the shape of the reference waveform  $< 5\text{ps}$
- Systematics from fit procedure  $< 5\text{ps}$
- Systematics from intensity dependence  $\sim 5\text{ps}$

# Other IRST devices

SiPM type without optical trench

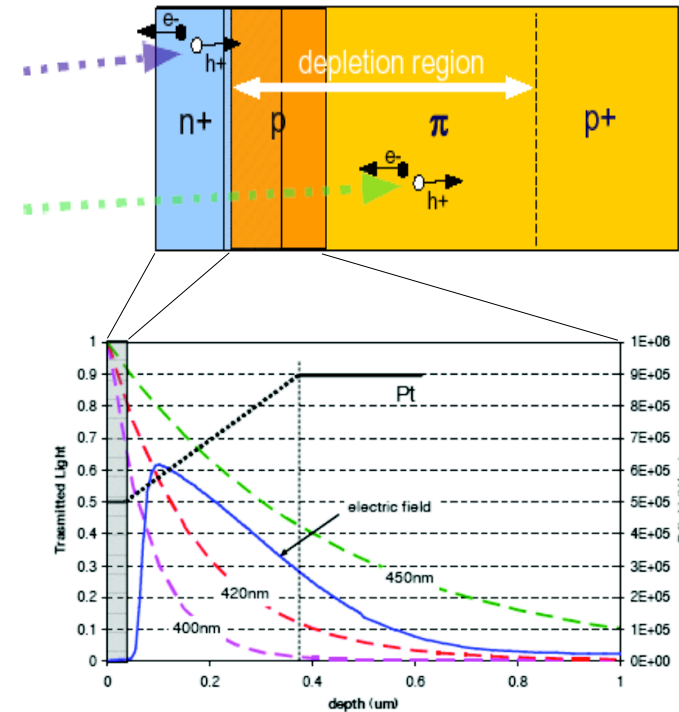


SiPM type with optical trench



Results in fair agreement for devices with the same structure

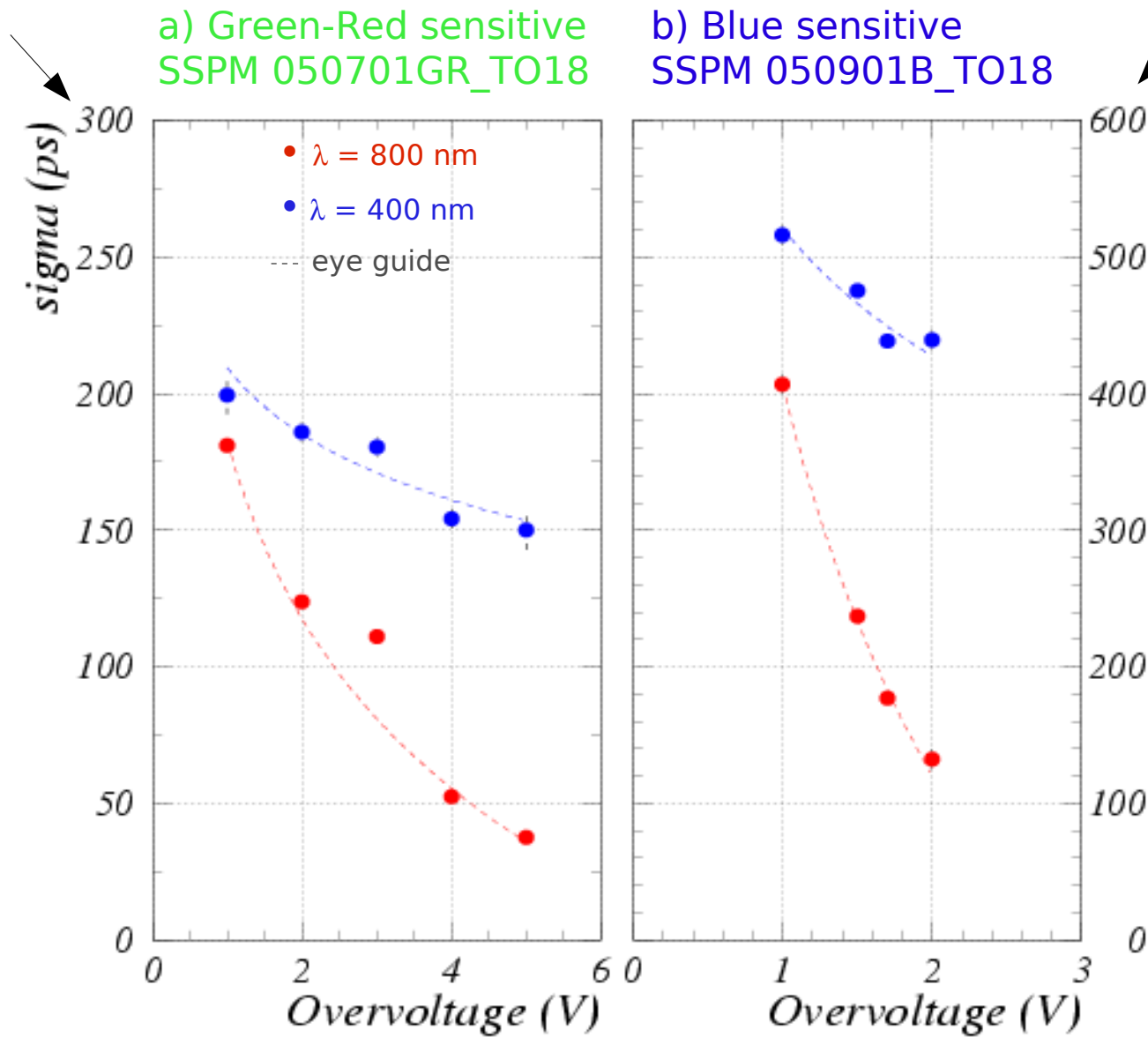
Better resolution for short wavelengths: carriers generated next to the peak of high E field ...



Quantitative comparison with models of time evolution of the avalanche and simulations:  
 WORK in PROGRESS



# Comparison with Photonique devices



Better resolution for long wavelengths: ?

Two different structures:

a)  $n^+/p$  not particularly shallow junction

b)  $p^+/n$  even deeper junction

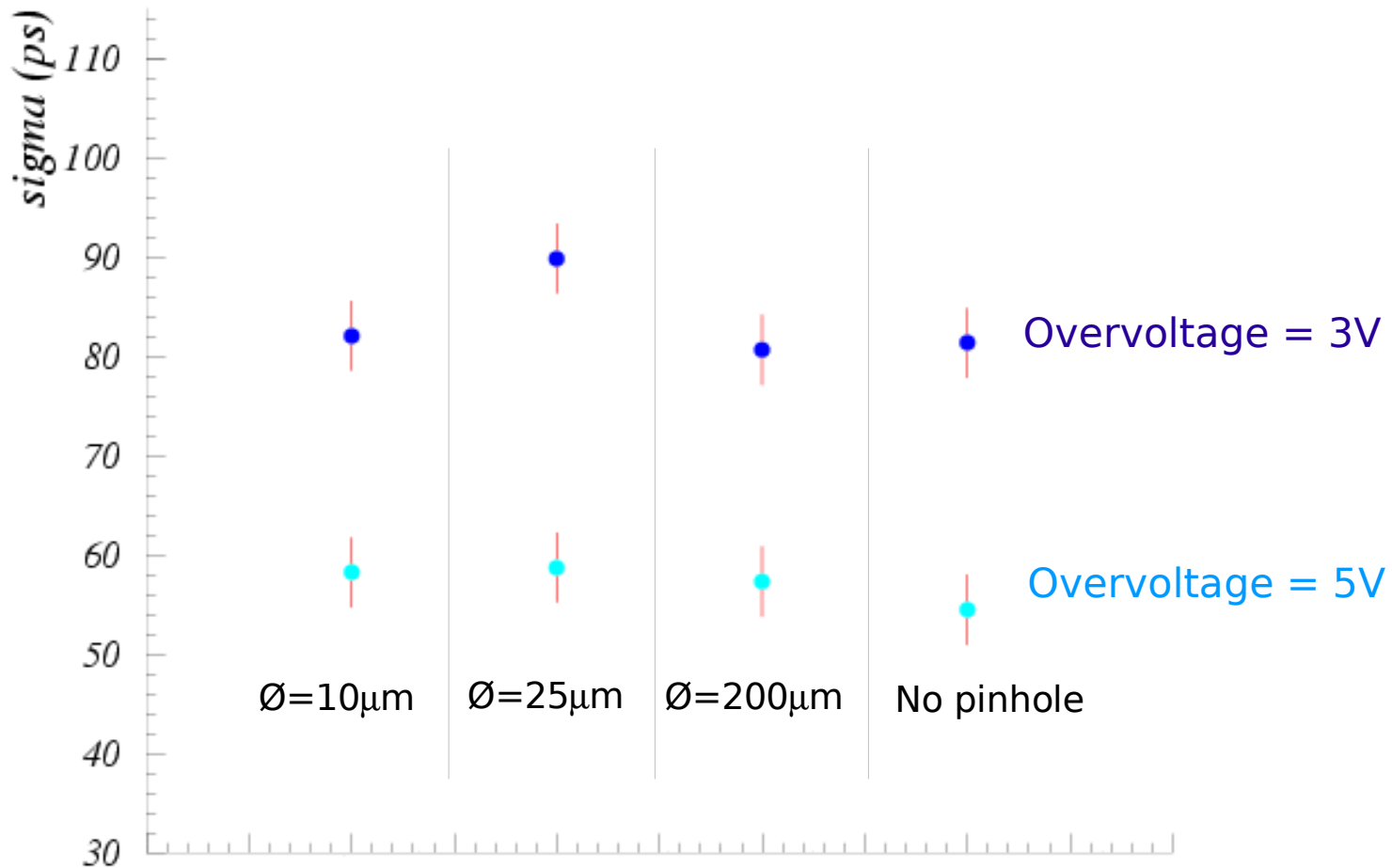
(?) WLS on entrance window

(?) kind of buried junction

# Dependence on the light spot size

IRST devices:

Measurement with a pinhole in front of SiPM to have different laser light beam size.



No relevant spread

→ Uniformity of rise-time among different cells

# Dependence on the number of photons

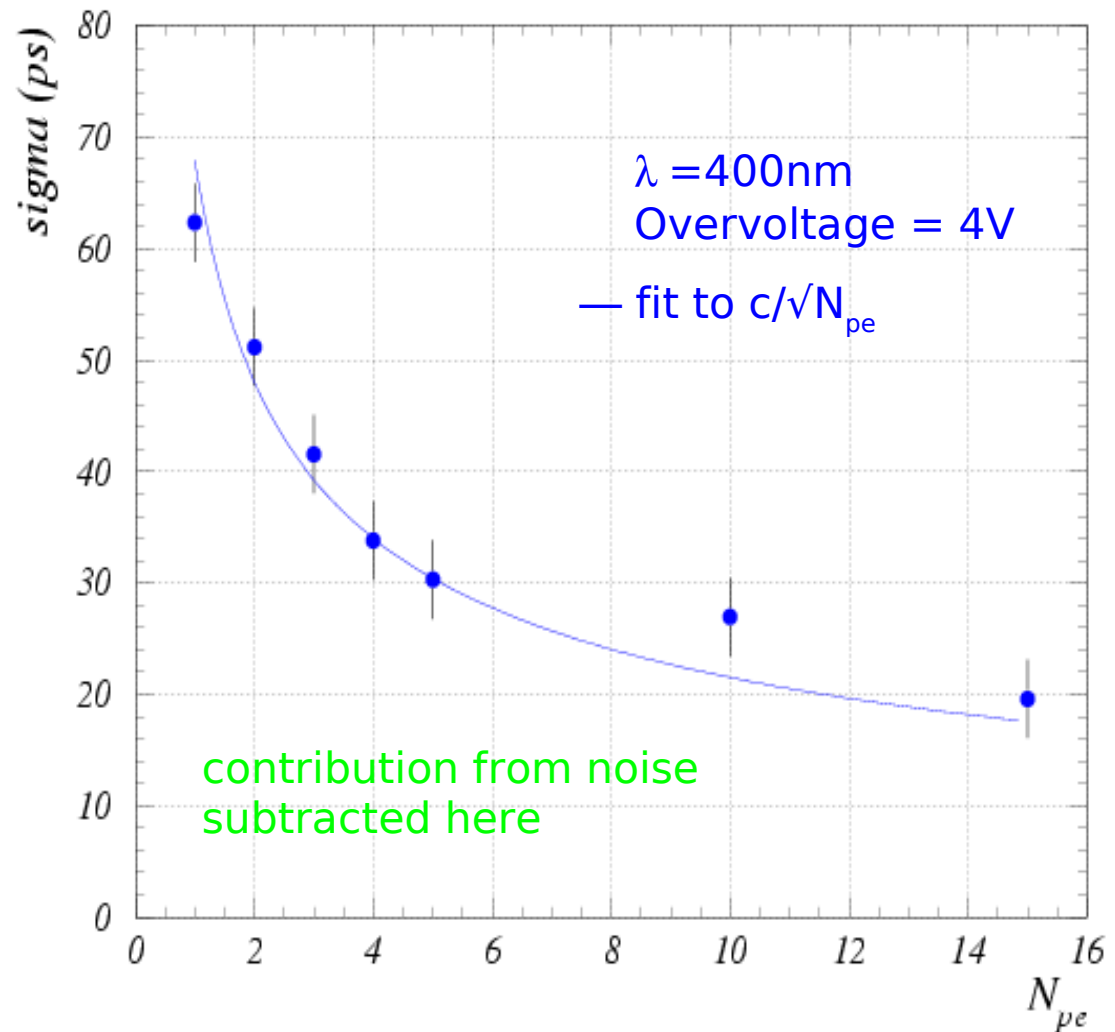
IRST devices:

Poisson statistics:

$$\sigma_t \propto \sqrt{N_{pe}}$$

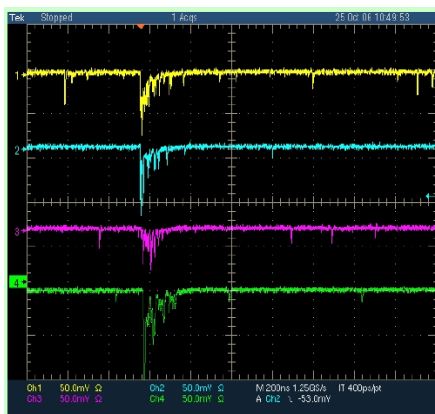
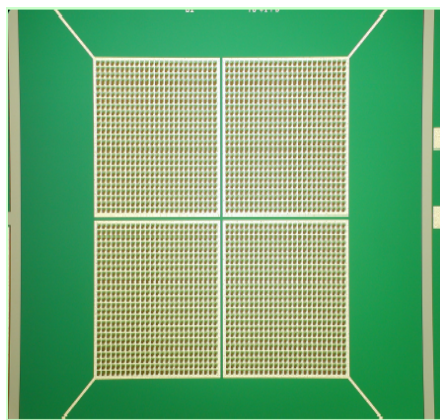
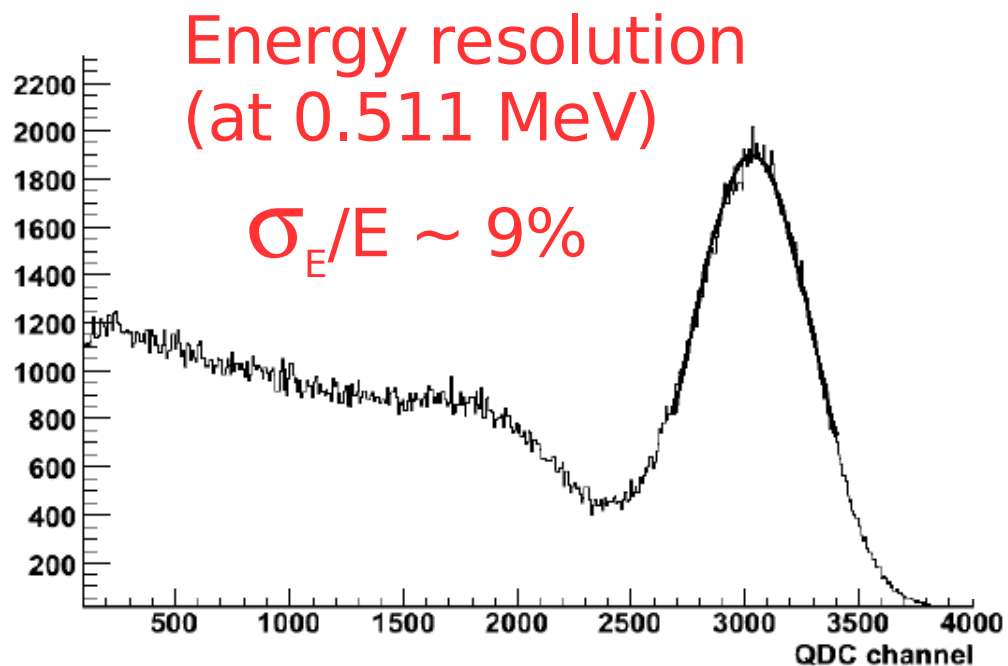
Simultaneous photons yielding 100pe might result in a resolution at the level of 10ps

(WORK is in PROGRESS to study timing with scintillators)



# Energy resolution with LSO

$^{22}\text{Na}$  spectrum with  
 $1 \times 1 \times 10 \text{ mm}^3$  LSO crystal  
( $\lambda_{\text{peak}} \sim 420 \text{ nm}$ ) coupled  
to a SiPM.



The first matrices of  $2 \times 2$  SiPMs have been developed (IRST). Currently they are being tested (Pisa) by coupling to  $2 \times 2 \times 20 \text{ mm}^3$  LSO crystals.

# Next steps and improvements

## 1) geometry optimization new layout ready with:

- increased fill factor  $\varepsilon_{\text{geom}} =$ 
  - 40x40 $\mu\text{m}$   $\rightarrow$  44%
  - 50x50 $\mu\text{m}$   $\rightarrow$  50%
  - 100x100 $\mu\text{m}$   $\rightarrow$  76%
- devices with larger area.

## 2) On the technological side:

- **dark count reduction** (gettering)
- **buried-junction SiPM** (photo-generation in the p-side of the junction  $\rightarrow$  higher avalanche triggering probability due to electrons higher ioniz. rate)  
[C.Piemonte, NIM A568 \(2006\) 224-232](#)

# Conclusions

SiPM might really replace PMT in many applications, due to their

- sensitivity to extremely low photon fluxes
- extremely fast response

IRST developed devices with excellent sensitivity to blue:

- devices working as expected
- very good reproducibility of the performances
- good yield
- good understanding of the device

Photo-detection efficiency (IRST devices):

- Quantum efficiency: > 95% in the blue region (optimized for 420nm)
- Triggering probability: growing linearly with overvoltage; could be optimized with buried-junction structure soon available
- Geometrical fill factor: 15-30% to be optimized → 44-76% soon available

Single photon timing resolution (IRST devices):

- $\sigma_t$  at the level of 70ps for typical working overvoltage (4V)
- Non gaussian tails: no relevant slow tails for short wavelengths; long wavelengths show slow ( $\tau < ns$ ) tails (diffusion ?) contributing at 10-30%
- Work in progress on non gaussian tails, simulation, timing with scintillators



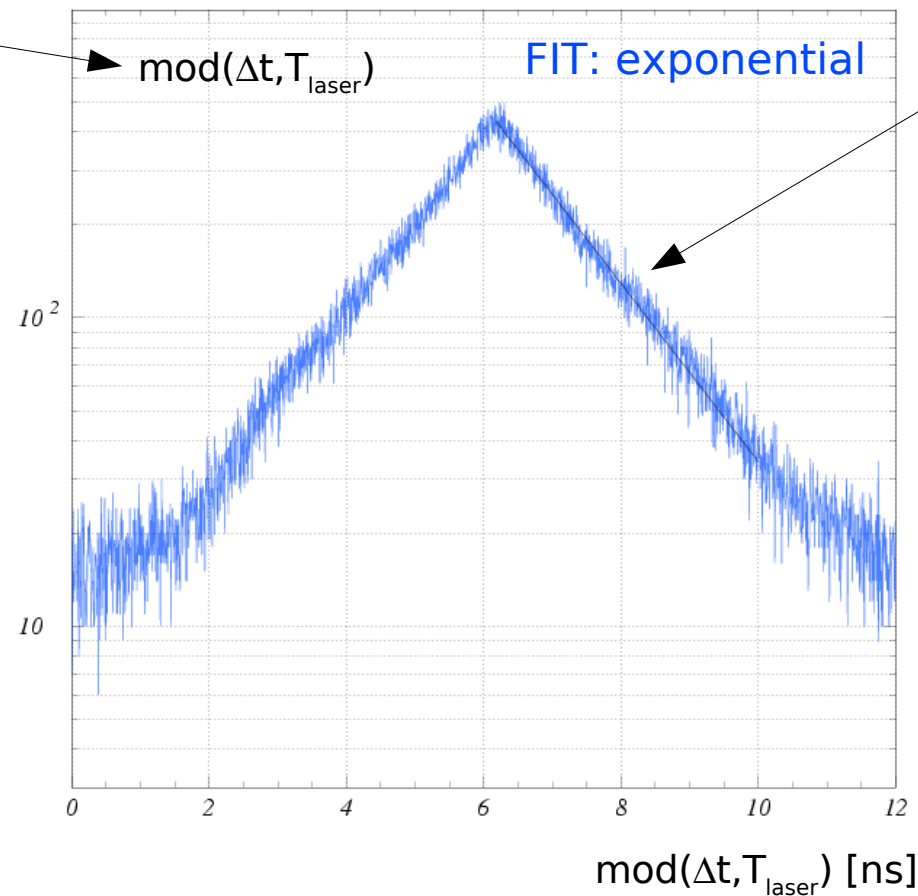
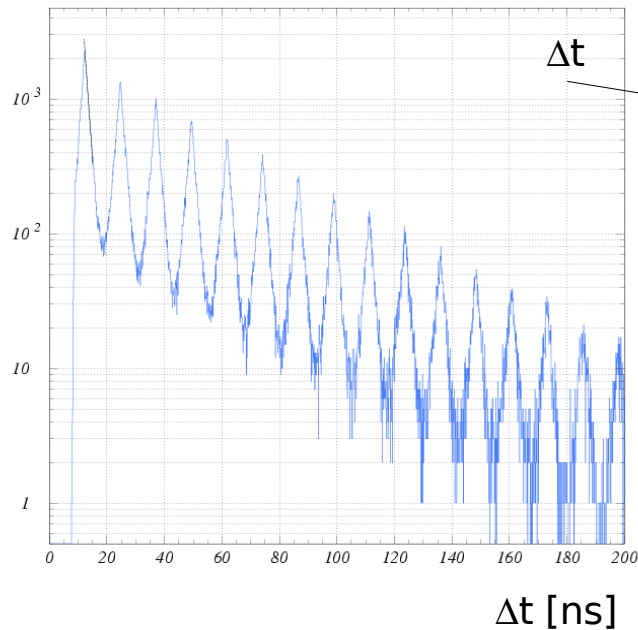
# Additional information

---

# Time differences distribution

Cross check: SiPM coupled to a fast plastic scintillator  $2 \times 2 \times 15\text{mm}^3$   
Only the scintillator exposed to the laser blue light  $\lambda=400\text{nm}$ .  
No direct laser light to the SiPM

→ measurement of the scintillator decay tail

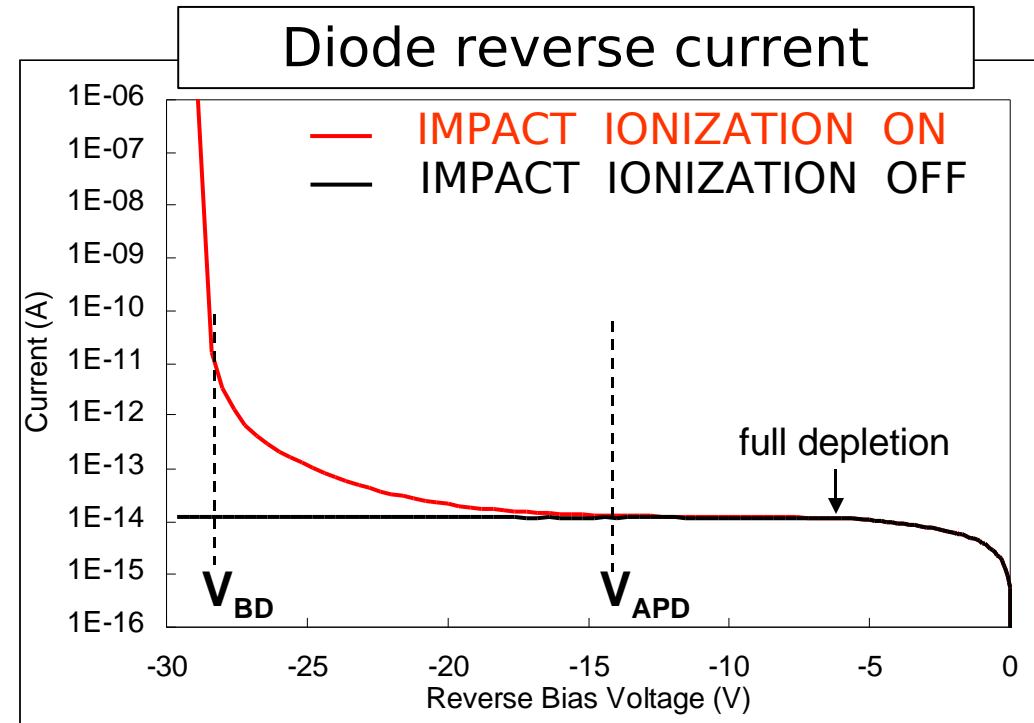
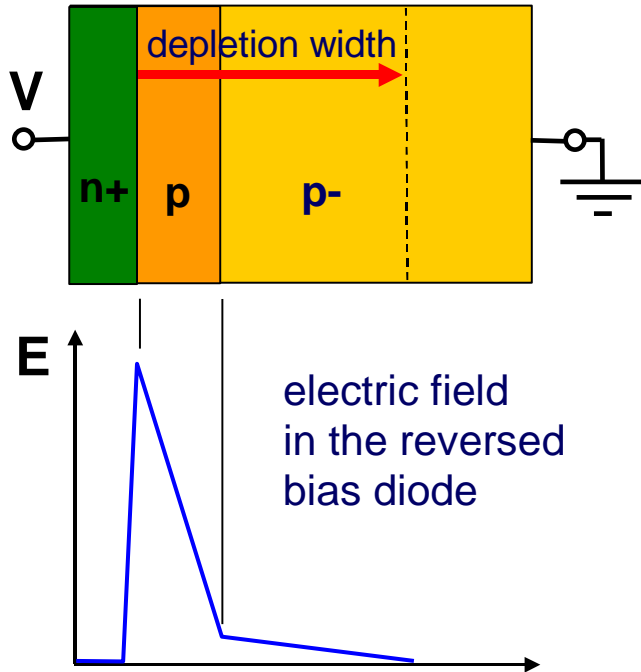


Measured scintillator decay time  $\tau \sim 1.5\text{ns}$



# Operation principle of a SiPM

diode structure



$V < V_{APD}$   $\Rightarrow$  photodiode

$V_{APD} < V < V_{BD}$   $\Rightarrow$  APD

$V > V_{BD}$   $\Rightarrow$  Geiger-mode APD

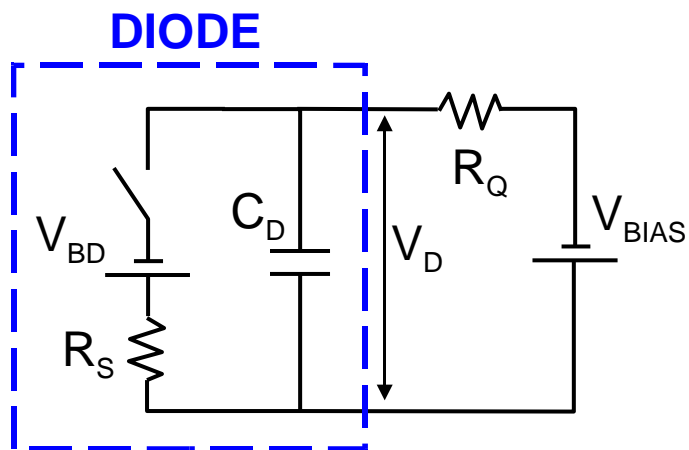
1 collected pair/generated pair

$\langle M \rangle$  collected pairs/generated pair

inf. collected pairs/generated pair

# Building block of a SiPM: Geiger-mode APD

The Geiger-Mode APD can be modeled with an electrical circuit and two probabilities:



- $C_d$
- $R_s$
- $V_{bd}$
- $R_q$
- $V_{bias} > V_{bd}$
- $P_{01}$
- $P_{10}$

OFF condition:  
switch open,  
capacitance charged to  $V_{BIAS}$ ,  
no current flowing

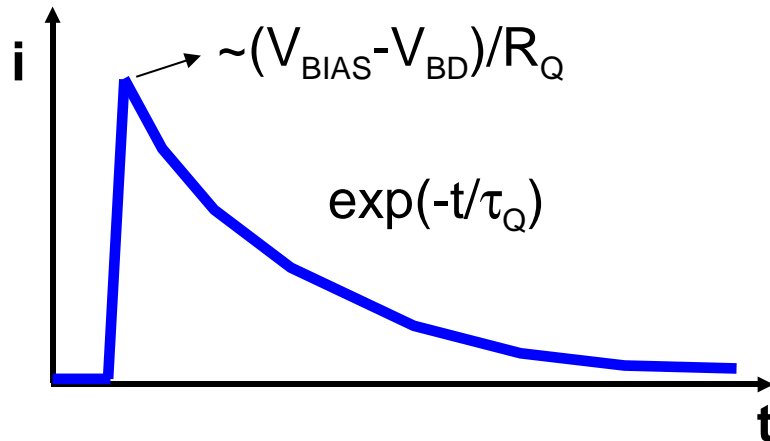
$P_{10}$  = turn-off probability  
probability that the number of carriers  
traversing the high-field region fluctuates  
to zero.

$P_{01}$  = turn-on probability  
probability that a carrier traversing the  
high-field region triggers the avalanche

ON condition:  
avalanche triggered, switch closed  
 $\Rightarrow C_D$  discharges to  $V_{BD}$  with  
a time constant  $R_S \times C_D$ , at the same time  
the external current grows to  $(V_{BIAS} - V_{BD}) / R_Q$



# Gain in Geiger-mode APD



The first part of the signal is much faster than trailing edge, indeed:

1.  $R_S * C_D \ll R_Q * C_D$
2. turn-off mean time is very short

Charge collected per event is the area of the exponential decay which is determined by circuitual elements and bias.



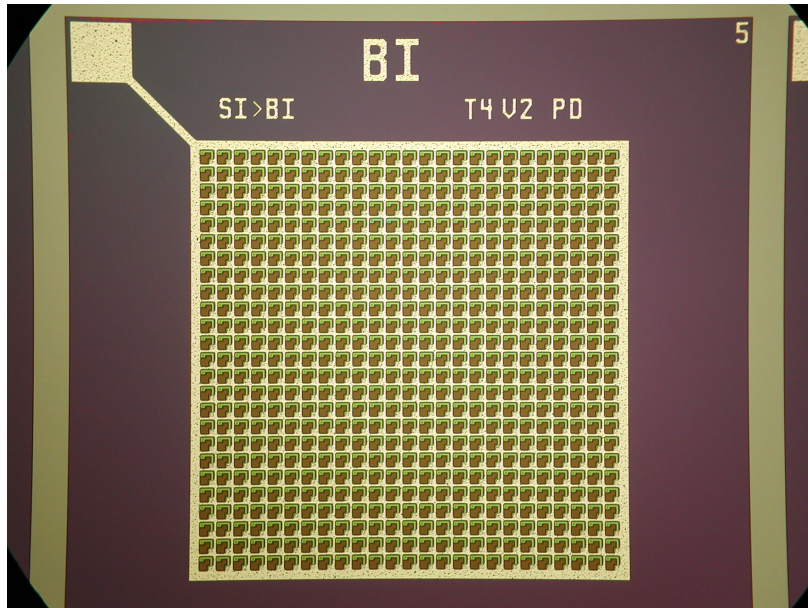
It is possible to define a GAIN

$$\text{Gain} = I_{\text{MAX}} * \tau_Q = \frac{(V_{\text{BIAS}} - V_{\text{BD}}) * \tau_Q}{R_Q} = \frac{(V_{\text{BIAS}} - V_{\text{BD}}) * C_D}{q}$$

This property is exploited in a Silicon photomultiplier

# The SiPM structure

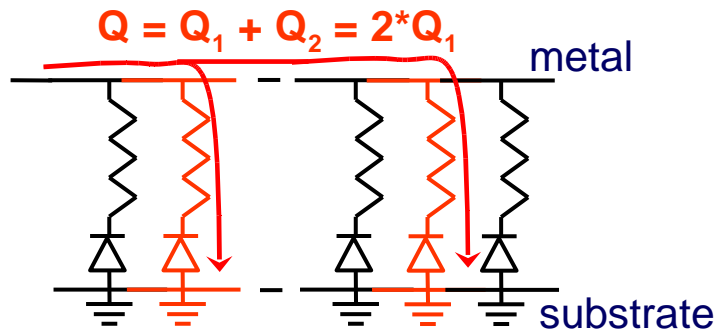
GM-APD gives no information on light intensity



first proposed by Golovin and Sadygov in the '90s

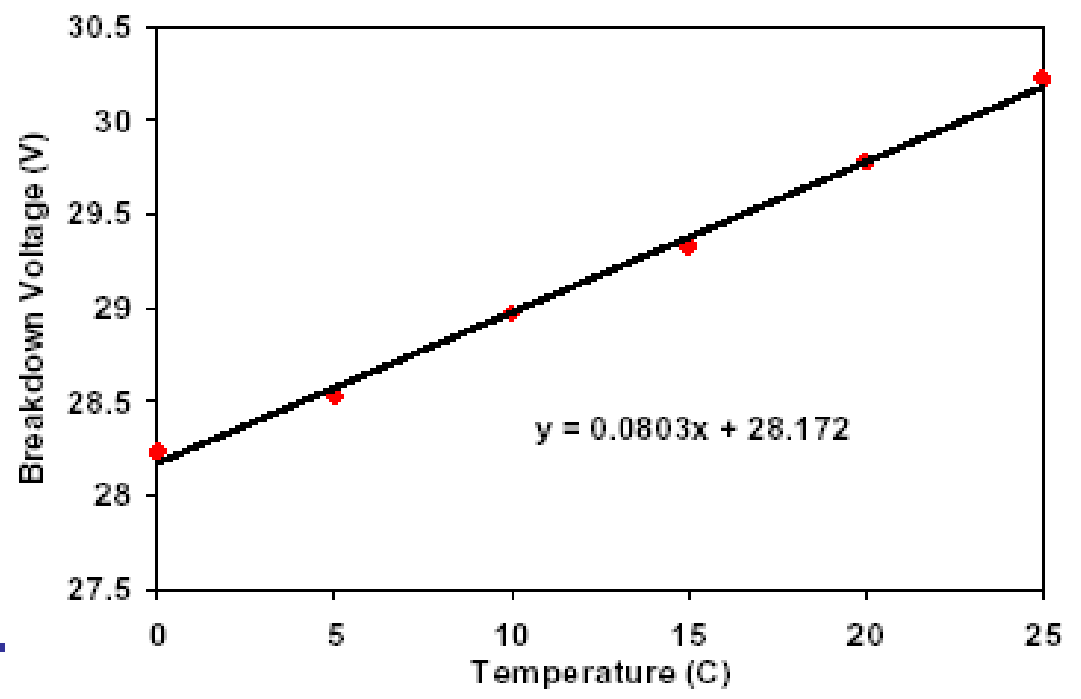
A single GM-APD is segmented in tiny micro GM-APD connected in parallel.

Each element is independent and gives the same signal when fired by a photon

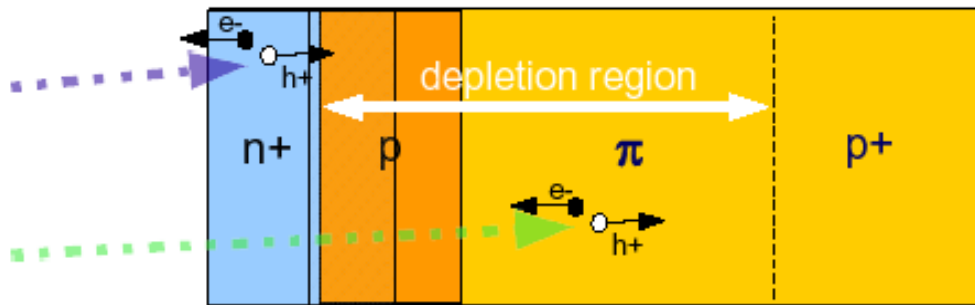


⇒ output charge is proportional to the number of triggered cells that, for PDE=1, is the number of photons

$V_{\text{breakdown}}$  vs  $T$



# Discussion



Pairs generated in the left side (short wl):  
e- collected, h+ trigger the avalanche

Pairs generated in the right side (long wl):  
h+ collected, e- trigger the avalanche

Rise time of the current generated by the device has two similar time scales:

\*  $\tau_{\text{disch.}} = R_S C_D$  discharge time constant (R of silicon and space charge)

\*  $\tau_{\text{ava.}}$  = Avalanche building-up

Order of magnitude ~ few x 100ps

Fluctuations of rise time (jitter) due to:

- 1) Carrier generation position: ~ 10ps/um depletion region
- 2) Avalanche multiplication (fluctuations)  
affecting the shape of the current leading edge: ~ 10 ps
- 3) Avalanche lateral spreading (limited by space charge and quenching mechanism) affecting the shape of the leading edge: ~

Pairs generated in the left side (short wl) next to the high field region:  
should give a “prompt” signal: only (2)+(3) involved

Pairs generated in the right side (long wl):

also mechanism (1) involved

which should account for the observed difference in blu/red response